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CLAIMS

1. A semiconductor producing/examining device comprising:

5 a ceramic substrate having a conductor layer formed on the surface thereof or inside thereof; and a supporting case; in which an external terminal is connected to said conductor layer,

10 wherein a connection between said conductor layer and said external terminal is performed such that:

said external terminal is pressed on said conductor layer; or

said external terminal is pressed on another conductor layer connected to said conductor layer.

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2. The semiconductor-producing/examining device according to claim 1,

wherein

20 the connection between said conductor layer and said external terminal, or

the connection between said another conductor layer and said external terminal

is performed by using elasticity of an elastic body.

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25 3. The semiconductor-producing/examining device according to claim 1 or 2,

wherein

the connection between said conductor layer and said external terminal, or

30 the connection between said another conductor layer and said external terminal

is performed through a non-oxidizable metal layer.

a) 35 4. The semiconductor-producing/examining device according to any of claims 1 to 3,

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wherein on a face of said ceramic substrate, which is the face opposite to the face for processing the semiconductor,

the connection between said conductor layer and said external terminal, or

- 5 the connection between said another conductor layer and  
said external terminal  
is performed.
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*add 2*